

Special Issue

Novel 3D Display Technology towards Metaverse

Message from the Guest Editor

Three-dimensional display has been humankind's dream since the birth of science. The fast-growing field of photonics, optoelectronics, and computer science has attracted broad interest in 3D development. We have never been so close to our dream of creating realistic virtual environments. Nevertheless, there are still significant challenges in 3D display. For example, the critical parameters such as field of view, resolution, 3D depth, and form factor cannot currently be satisfied simultaneously. In this Special Issue, particular focus will be paid to 3D-display-related optics and novel micro-nano technology. Potential topics include, but are not limited to, the following: (1) Novel 3D display architecture, hardware and applications; (2) Novel micro-nano optical technology for 3D display; (3) Novel optical devices for 3D display (especially welcome); (4) 3D imaging and 3D display technology. Please note that the papers of this Special Issue should be based on the scope of *Micromachines*. We look forward to receiving your contributions.

Guest Editor

Prof. Dr. Wen Qiao

School of Optoelectronic Science and Engineering, Soochow University, Suzhou 215006, China

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Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

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Message from the Editor-in-Chief

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Editor-in-Chief

Prof. Dr. Ai-Qun Liu

Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China

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